



PATENT APPLICATION

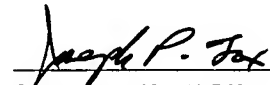
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Fujikawa et al.  
Serial No.: 10/795,788  
Conf. No.: 7705  
Filed: March 8, 2004  
For: EXPOSURE MASK AND  
PATTERN EXPOSURE  
METHOD  
Art Unit: 1756  
Examiner: Rosasco, Stephen D.

*I hereby certify that this paper is being deposited with the United States Postal Service as FIRST-CLASS mail in an envelope addressed to: Mail Stop ISSUE FEE, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this date.*

July 13, 2007

Date

  
Registration No. 41,760  
Attorney for Applicant(s)

**AMENDMENT AFTER NOTICE OF ALLOWANCE UNDER 37 C.F.R. 1.312**

Mail Stop ISSUE FEE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Prior to issuance of the above-named allowed Application, please enter the following amendments: